Frontier Applications of Metamaterials to Magnetic Confinement Fusion

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Plasmas and metamaterials have a long history of flirting with each other



 Artificial dielectrics [Kock 1946] applied to plasma diagnostics in 1980-90's (e.g. [Volpe-Laqua 2003] and refs. therein).

- In plasmas $\epsilon < 1$ and, at $\omega < \omega_p$, $\epsilon < 0$, as later realized in metamaterials.
- Similar to metamaterials, optical properties of plasma can be "engineered" by proper choice of n_e, n_i, T_e, T_i, B and their gradients.
- Pendry's 1996 seminal work on metamaterials mentions 'plasma' and 'plasmons' 42 times.
- Plasmons and magnetoplasmons reminiscent of plasma waves and Electron Bernstein Waves in plasmas



Outline

- Motivation
- Reverse chromatic aberration
- Metamaterial lens
- Numerical opimization
- Ink-jet manufacturing
- Rapid frequency-controlled steering



Example of special needs of plasma diagnostics that can be addressed by metamaterials

- Electron Cyclotron Emission is microwave emission from gyrating electrons in magnetized plasmas
- Important for temperature measurement
- Emission at different frequencies *f* originates at different locations → Challenge for focusing:

focal length should vary dramatically (*increase*) with f

- This "reverse" chromatic aberration cannot be obtained with convergent lenses of *conventional* materials.
- It can be obtained with a *metamaterial* lens.



High sensitivity of focus to *f* might find application in survey, satellite observations, directed energy.

- If object to be detected/irradiated is
 - Moving
 - Non-monochromatic
- And sensor/receiver is rapidly (electrically) tunable
- Then rapid change of $f \rightarrow$ rapid change of focus
- No moving parts in the optics



Control of chromatic aberration at design stage and rapid inexpensive ink-jet manufacturing also have numerous applications

- Reverse chromatic aberration lens can compensate for regular chromatic aberration of other lenses in optical system
- Flat lens of *zero* chromatic aberration can be designed and manufactured by same methods
- Ink-jet printing can be applied to RF IC circuits, antennas, magnetic sensors, etc.
- It can allow rapid prototyping, manufacturing and customization to specific frequency, polarization, focus etc.



What is "reverse" Chromatic Aberration?





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Sandwiches of inductive and capacitive layers behave like LC transmission lines





2D array of LC filters imparting different $\Delta \phi$ behaves like a Fresnel lens





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Designed, built and testing a 7 zone RCA lens for 8-12 GHz. Designed an 83 zone RCA lens for 80-130 GHz.



Reverse Chromatic Aberration is obtained by imposing vast zone-tozone variation of $\Delta \phi$ at low *f* and more uniform response at high *f*





Geometrical dimensions can be analytically optimized to obtain desired $\Delta\phi(f)$ in each zone

$$L = \mu_{0}\mu_{eff} \frac{D}{2\pi} \ln \left[\frac{1}{\sin \left(\frac{\pi W}{2D} \right)} \right] \qquad C_{1} = \epsilon_{0}\epsilon_{eff} \frac{2D}{\pi} \ln \left[\frac{1}{\sin \left(\frac{\pi g_{1}}{2D} \right)} \right]$$

$$\frac{Z_{0}}{\frac{1}{2}C} \frac{Z,h}{\frac{1}{2}L} \frac{Z,h}{\frac{1}{2}C} \frac{Z,h}{\frac{1}{2}L} \frac{Z,h}{\frac{1}{2}C} \frac{Z_{0}}{\frac{1}{2}L} \frac{Z_{0}}{\frac{1}{2}C}$$

$$\frac{T = \frac{2}{A + \frac{B}{Z_{0}} + CZ_{0} + D}}{\left[\frac{1}{j\omega C_{1}} \right] \left[\frac{\cos\beta h}{jZ} \sin\beta h} \cos\beta h \right] \left[\frac{1}{j\omega L} \frac{0}{1} \right] \left[\frac{\cos\beta h}{jZ} \sin\beta h} \cos\beta h \right] \left[\frac{1}{j\omega C_{2}} \frac{0}{1} \right] \times$$

$$\left[\frac{\cos\beta h}{jZ} \sin\beta h} \cos\beta h \right] \left[\frac{1}{j\omega L} \frac{0}{1} \right] \left[\frac{\cos\beta h}{jZ} \sin\beta h} \cos\beta h \right] \left[\frac{1}{j\omega C_{1}} \frac{0}{1} \right]$$

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... or problem can be solved numerically

- Single cell of dimensions *D*, *w*, *g*₁, *g*₂, etc. is modeled with finite element code (CST).
- Transmittance T and phase-shift $\Delta \phi$ at various frequencies f_1, f_2 , etc. are stored.
- Calculation is repeated for various D,
 w, g₁, g₂, etc. Database is built.
- For each zone, we pick D, w, g_1 , g_2 , etc. yielding best match between calculated T and $\Delta \phi$ and desired Tand $\Delta \phi$

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Numerically optimized $\Delta \phi(f)$ matches desired $\Delta \phi(f)$ for RCA at *f*=8-12GHz



W.J. Capecchi et al., Optics Express 20, 8761 (2012)

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Database was also built for f=80-130 GHz (ECE at DIII-D)



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Relaxing constraints on *absolute* phase improves agreement with desired $\Delta\phi(f)$



G="Goal function" (the smaller the better)

K.C. Hammond et al., J Infrared Milli Terahz Waves 34, 437 (2013)

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Individual fine-tuning of geometrical parameters in each layer further improves the agreement



d

Optimized cells put together and treated as attenuated and delayed dipole-emitters \rightarrow Interference pattern \rightarrow Global lens response





Obtained desired RCA for maximum transverse resolution in ECE at at DIII-D. A single lens focuses different *f* at different locations where that *f* is EC-emitted.



Sidelobes were explained with non-uniform transmissivity across zones \rightarrow grating \rightarrow diffraction maxima





Simulations show that varying the lens aperture changes its focal length \rightarrow a diaphragm acting as a zoom!



EC-emitting locations are always in focus, with metamaterial lens. They are not in focus with present mirror.



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Ink-jet printing is capable of 1-5 μ m details







Silver, lines: 3µm, spacing: 15µm Gold, lines: 5µm, spacing: 50µm



Conventional printer





CAD

Super-fine Printer

K. Takano *et al.,* Applied Phys. Expr. 2010 Sjctechnology.com



Low-power 8-12 GHz lens manufactured using an ink-jet printer and silver-nanoparticle ink

- (show samples)
- Ink = liquid suspension of ~5nm Ag nanoparticles
- Resistivity $3\mu\Omega cm$ after 1h sintering at 150-200°C (bulk Ag 1.6 $\mu\Omega cm$).
- Printed circuit board (PCB) techniques (e.g., laser) also under consideration
- 80-130 GHz might require lithography, laser raster or integrated circuit (IC) nano/microfabrication techniques
- Tests of 8-12 GHz lens starting soon



Extension to high power requires modified design and materials

- Some motivations:
 - Tunable gyrotrons
 - Rapid steering of ECCD for NTM stabilization w/o moving mirrors in vessel
 - Collective Thomson
 Scattering
- Simple! Replace:
 - plastic dielectric → recirculating cooling fluid (freon FC-75)
 - Square patches → stripes
 (2 sets, orthogonal)



Frequency-controlled Steering

- Same num. technique can be used:
 - Prescribe $\Delta \phi(f)$ for each cell
 - Different spatial profiles of $\Delta \phi(f)$
- "Super-diffractor": diffraction grating of metamaterial-enhanced resolving power
- High sensitivity to *f* important



Conclusions

- Proper array of microfabricated phase-shifters acts as a lens.
- Optimizing its dimensions allows to match a desired dependence of focal length on frequency, including extreme and reverse chromatic aberration.
- Numerical example for 8-12 and 80-130 GHz.
- Lens for 8-12 GHz was manufactured by ink-jet printing (with silver nanoparticle ink) on dielectric substrate.
 - Inexpensive, fast, suited for low-power, low-frequency.
 - Alternatives at high-power and/or high-frequency were discussed.
- Numerical technique can be extended to:
 - aberration-free lens
 - rapid frequency-controlled steering
- With different designs and materials, manufacturing can be extended to high-power heating, current drive & active
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